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## On the Origin of Laser-Induced Surface Activation of Ceramics

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# ON THE ORIGIN OF LASER-INDUCED SURFACE ACTIVATION OF CERAMICS

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## ABSTRACT

The surfaces of  $\text{Al}_2\text{O}_3$  and  $\text{AlN}$  are modified by pulsed-laser irradiation. This modification promotes the deposition of copper when the irradiated substrates are immersed in an electroless bath. In this paper the nature of the surface modification is analyzed using results from Auger Emission Spectroscopy (AES) and Cross Sectional Transmission Electron Microscopy (XTEM). During irradiation  $\text{AlN}$  thermally decomposes leaving a discontinuous metallic film on the surface. A film of  $\text{Al}_2\text{O}_3$  is detected at the surface of the irradiated  $\text{AlN}$  substrate, much thicker when the irradiation is performed in an oxidizing atmosphere than when done in a reducing one. Nanoparticles of metallic aluminum are generated during laser irradiation of  $\text{Al}_2\text{O}_3$  in a reducing atmosphere. When the irradiation of  $\text{Al}_2\text{O}_3$  is performed in an oxidizing atmosphere, regions containing aluminum or substoichiometric alumina are detected by AES. It is concluded that the presence of metallic aluminum is the main reason why electroless deposition can occur in both  $\text{AlN}$  and  $\text{Al}_2\text{O}_3$ . Deposition kinetics are completely consistent with this conclusion. It is very likely that also substoichiometric alumina helps to catalyze the electroless deposition.

## INTRODUCTION

In the process known as laser-induced surface activation of dielectric materials a given pattern is imprinted on a substrate by laser irradiating its surface. The pattern can be produced by laser-scanning or by illuminating the substrate through a mask. When the substrate thus treated is immersed in an electroless solution, a metallic film is deposited in the laser-exposed area only. Surface activation can be conducted many weeks ahead of the electroless deposition. Excimer, argon ion, copper-vapor and  $\text{CO}_2$  lasers have been used (1 - 7) to activate the surface of a variety of materials including ionic and covalent oxides, a nitride, a polymer and diamond films. All of the ceramic materials that have been laser activated for electroless metal deposition have a low absorption coefficient or are transparent to low power density ultraviolet radiation in their single-crystalline forms. In this work, careful surface characterization of irradiated substrates have led us to understand why electroless copper deposition takes place in the laser irradiated area.

## CHARACTERIZATION OF LASER IRRADIATED $\text{Al}_2\text{O}_3$ AND $\text{AlN}$ SUBSTRATES

The effects of 308 nm-wavelength laser irradiation on  $\text{Al}_2\text{O}_3$  (8) and  $\text{AlN}$  under reducing and oxidizing atmospheres have been studied by transmission electron microscopy (TEM) (9), x-ray photoelectron spectroscopy (XPS) (10) and Auger emission spectroscopy (AES). AES is particularly well suited to analyze the chemical changes because it can resolve unambiguously the chemical state of aluminum, whether in a metallic, in an oxide or in a nitride environment. The Auger electron kinetic energy for the LVV transition of aluminum in  $\text{AlN}$  is 5 eV higher than the corresponding value for the oxide. The energy for the LVV transition of aluminum in a metallic state is 9 eV higher than the corresponding value for the nitride. Therefore it is relatively simple to resolve the chemical state changes of these materials with AES.

The surface of as-received  $\text{AlN}$  consists mostly of  $\text{Al}_2\text{O}_3$  layers, as can be seen in Figure 1. This is consistent with  $\text{Al}_2\text{O}_3$  being thermodynamically more stable than  $\text{AlN}$  (11). Thus, mechanical and/or thermal processing in air induces oxidation of the  $\text{AlN}$  surface. Spectra ii and

iii shown in figure 1 were taken at increasing depths. They demonstrate that as the distance to the surface increases the chemistry changes from  $\text{Al}_2\text{O}_3$  to  $\text{AlN}$ , as expected.

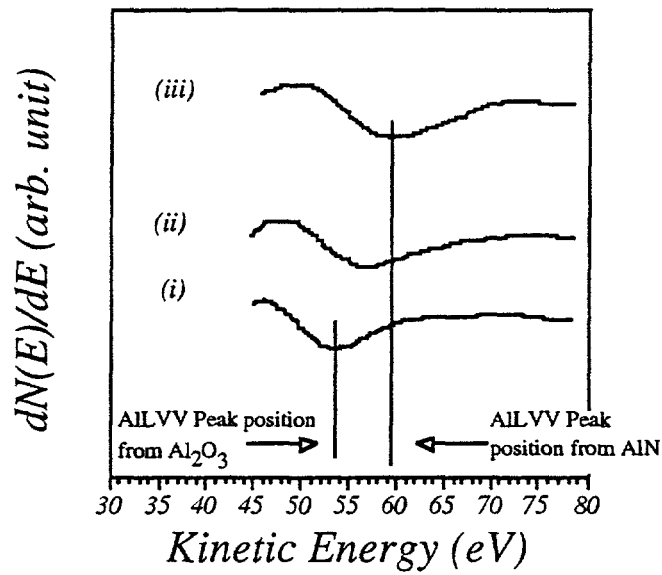


Figure 1. Al LVV peak spectra from the surface (i) and the subsurface (ii and iii, at increasing depth), of as-received  $\text{AlN}$  substrate. To obtain the subsurface AES peaks the surface was gently sputter-etched in situ. The spectrum from the surface is that of stoichiometric alumina (i). As sputter etching advances to deeper substrate layers, the surface chemistry changes from aluminum oxide to aluminum nitride.

Figure 2 shows the Al LVV peaks from the surface and from the interior of an  $\text{AlN}$  substrate laser-irradiated at  $2 \text{ J/cm}^2$  in a reducing atmosphere ( $\text{Ar-4\%H}_2$ ). The surface is mostly  $\text{Al}_2\text{O}_3$  and,

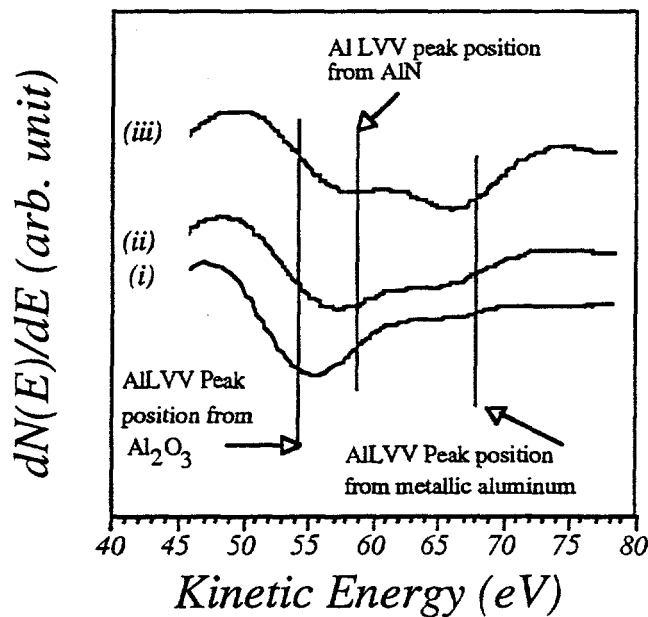


Figure 2. Al LVV peak spectra from the surface (i) and subsurface (ii and iii) of  $\text{AlN}$  laser-irradiated in  $\text{Ar-4\%H}_2$  at  $4 \text{ J/cm}^2$ . Al LVV from the surface (i) is a superposition of peaks from  $\text{Al}_2\text{O}_3$  and  $\text{AlN}$ , while sputter etching reveals that the subsurface peaks are from both  $\text{AlN}$  and metallic aluminum (ii and iii).

as the surface layers are removed, metallic aluminum appears together with  $\text{Al}_2\text{O}_3$ . Deeper inward the substrate consists of metallic aluminum and  $\text{AlN}$ . The amount of metallic aluminum at level (iii) is larger than the amount of aluminum in  $\text{AlN}$  form (Figure 2). The oxide layer after laser irradiation is one to two monolayers thick, whereas that of as-received  $\text{AlN}$  was much thicker, but varied depending on the area. After laser irradiation in a reducing atmosphere  $\text{AlN}$  decomposes and a relatively thick layer of aluminum is formed. This implies that the laser irradiation increases the temperature above the decomposition value (12). When the specimen is exposed to air the aluminum is oxidized forming aluminum oxide. The decomposition of  $\text{AlN}$  is thermally induced and, hence, it takes place even if the irradiation is performed in air or in pure oxygen. When the irradiation is performed in an oxygen-rich atmosphere, however, the oxide layer is significantly thicker. This is not surprising because the aluminum layer that results from the decomposition is exposed to oxygen at high temperatures.

Auger mapping (13) and cross sectional TEM (9) revealed that metallic aluminum produced by laser-induced decomposition clustered in the  $\text{AlN}$  matrix.

An AES study was conducted in alumina in a similar manner to the study in aluminum nitride. Alumina substrates were irradiated in oxygen and in  $\text{Ar-4\%H}_2$  at  $2 \text{ J/cm}^2$ . The surface chemical composition of the specimen irradiated in oxygen corresponds to  $\text{Al}_2\text{O}_3$ , while in the subsurface regions metallic aluminum and/or substoichiometric aluminum oxide is observed (Figure 3).

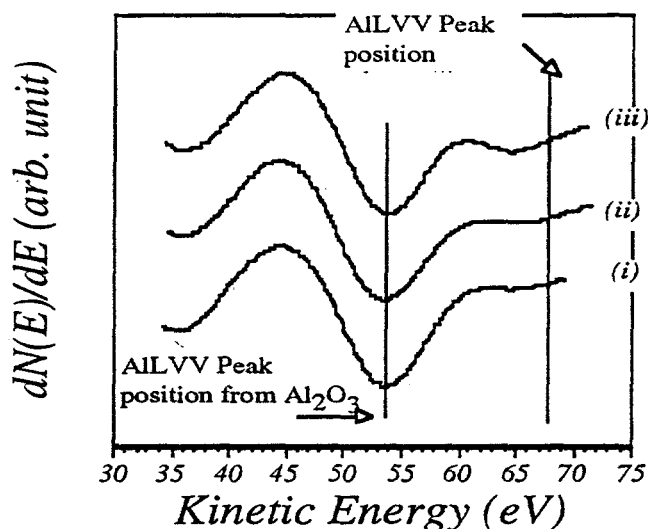


Figure 3. Al LVV peaks from the surface (i) and subsurface (ii and iii) of alumina laser irradiated in air at  $2 \text{ J/cm}^2$ . Metallic and/or substoichiometric aluminum oxide is detected in the subsurface region.

The specimen irradiated in  $\text{Ar-4\%H}_2$  shows much more aluminum in the subsurface than the specimen irradiated in oxygen (figure 4). However, the amount of metallic aluminum in the  $\text{Ar-4\%H}_2$  irradiated alumina is much less than that formed in the aluminum nitride, as can be seen by comparison of the peak-to-peak heights of Al LVV peaks from metallic aluminum,  $\text{Al}_2\text{O}_3$  and  $\text{AlN}$  (Figures 2 and 6). Substoichiometric alumina and/or metallic aluminum are detected in the irradiated sample even if the irradiation was done in an oxidizing atmosphere. These results thus demonstrate that during laser processing thermal decomposition of alumina takes place, independent of the irradiation atmosphere. Remarkably, XPS spectra (9) reveal that the amount of oxygen present in alumina laser irradiated in air is higher than in unirradiated substrates. EDS analyses confirmed that the oxygen content is higher in substrates irradiated in air than in as-received ones. It seems that a significant amount of oxygen is trapped into positions other than lattice sites. This rationale is supported by the observation that, after irradiation, the samples acquire a strong yellow-brownish color, characteristic of F centers.

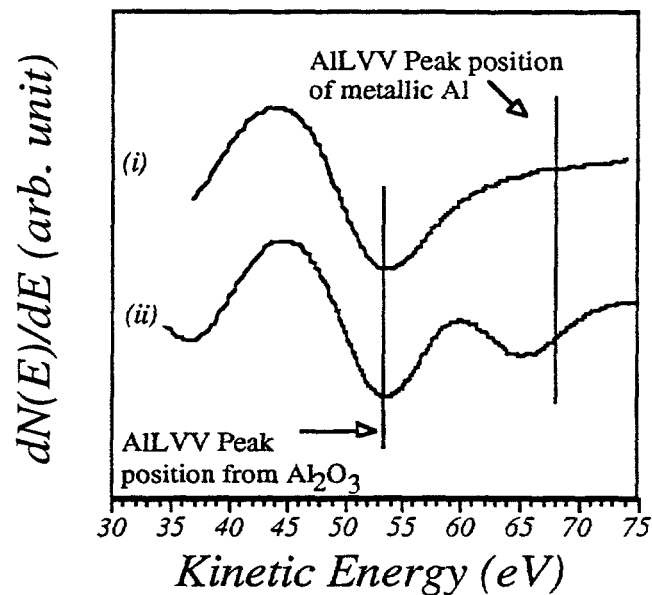


Figure 4. Al LVV peaks from the surface (i) and subsurface (ii) of alumina laser-irradiated in Ar-4% $H_2$  at  $2J/cm^2$ . More metallic aluminum is left after irradiation in a reducing atmosphere than in an oxidizing atmosphere (shown in Fig. 3).

Figure 5 is a cross sectional transmission electron micrograph of an  $Al_2O_3$  substrate irradiated in Ar-4%  $H_2$ . A  $0.5\ \mu m$ -thick layer of  $Al_2O_3$  has been melted and it resolidified with a cellular structure also including a high density of small particles in a  $0.34\ \mu m$ -thick layer (figure 5a). In figure 5b the sample has been rotated to offer a better view of the particles. The spacing between lattice fringes observed when some of these small particles were imaged with high resolution corresponds to the spacing of aluminum (111) planes. The distribution of the aluminum particles suggests that their formation is related to gas evolution during solidification. Thus, it can be reasoned that atmospheric hydrogen dissolved in the liquid alumina is pushed away during solidification increasing its concentration ahead of the advancing interface. When the hydrogen concentration at the interface reaches a value high enough to start reducing  $Al_2O_3$ , liquid metallic aluminum should form by reduction of  $Al_2O_3$  in front of the interface. When these pockets of liquid aluminum solidify they become the particles observed by TEM.

#### LASER-INDUCED SURFACE ACTIVATION OF $AlN$ AND $Al_2O_3$

Laser-induced decomposition of  $AlN$  irradiated at or above  $2\ J/cm^2$  leaves on the surface enough aluminum to form an interconnected network of islands, as verified by the much lower electrical resistance of specimens irradiated at 2 and  $3\ J/cm^2$  compared to that of specimens irradiated at  $1\ J/cm^2$  (14). Moreover, the electrical resistance decreases as the laser density increases indicating that the amount of metallic aluminum increases as the applied laser energy density increases. After immersion in an electroless bath, the electrical resistances of the 2 and  $3\ J/cm^2$ -irradiated specimens rapidly increase, while that of the  $1\ J/cm^2$  specimen rapidly decreases. After a short period of immersion time the three specimens reach the same electrical resistance value. This value of electrical resistance is that of the measuring cell in the electroless solution (14). The metallic aluminum is mostly dissolved because the electroless bath contains  $NaOH$  which is well known to dissolve aluminum. We have observed by TEM that as the dissolution of aluminum progresses copper islands start forming at the same location (9). Thus, the partly dissolved aluminum film formed by the  $AlN$  decomposition acts as a catalyst for electroless deposition. Copper metallization is induced in the irradiated areas upon immersion of laser-treated substrates in a copper electroless bath. We have shown previously using TEM that

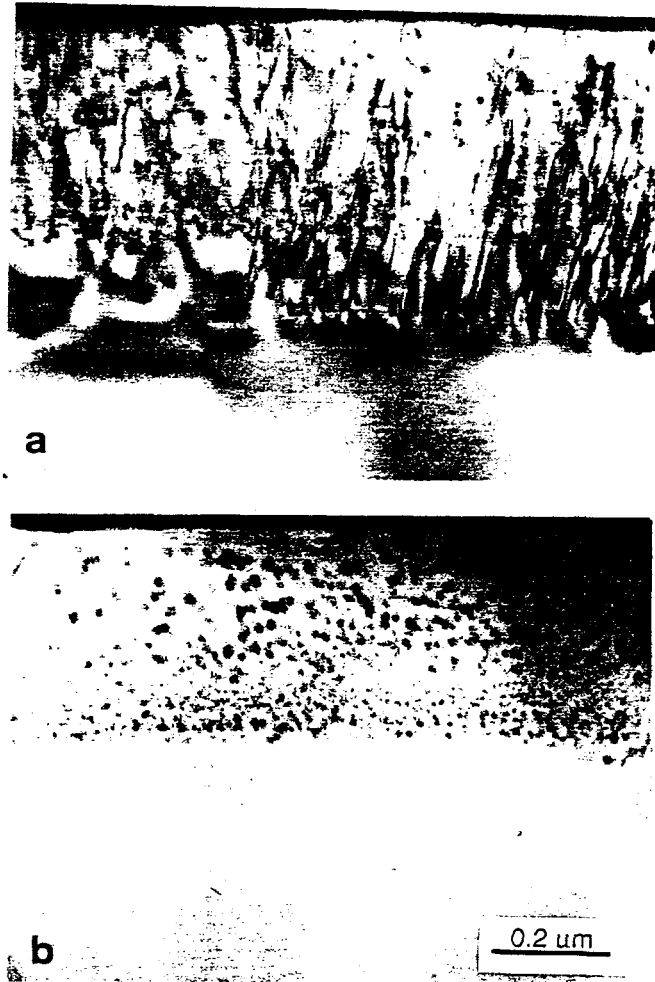


Figure 5. Cross sectional transmission electron micrograph of an  $\text{Al}_2\text{O}_3$  substrate irradiated in  $\text{Ar-4\% H}_2$  at  $1.6 \text{ J/cm}^2$ . a) A  $0.5 \mu\text{m}$ -thick layer of  $\text{Al}_2\text{O}_3$  has been melted and it resolidified with a cellular structure including a high density of small aluminum particles in a  $0.34 \mu\text{m}$ -thick layer. b) Specimen was slightly rotated to show only the metallic particles.

copper island appeared in the crevices and interfaces left by the dissolved aluminum islands (9). A galvanic displacement reaction in which aluminum is dissolved and copper is deposited is the most likely process start-up reaction (15). We deduce that, similar to what happens with  $\text{AlN}$ , the metallic aluminum detected by AES (Fig. 3 and 4) and shown in XTEM (Fig. 5) during laser irradiation of  $\text{Al}_2\text{O}_3$  must promote the deposition of electroless copper.

DeSilva et al. (15) measured the time required to initiate and complete the electroless deposition in  $\text{AlN}$  and  $\text{Al}_2\text{O}_3$  substrates irradiated in oxidizing and reducing atmospheres. Reducing irradiation atmospheres promote much faster electroless deposition rates because it takes a shorter time to dissolve a thinner oxide layer once the substrate is immersed in the electroless solution containing  $\text{NaOH}$ . At a given atmosphere and for a given laser energy density used for activation, the deposition of copper is much faster in  $\text{AlN}$  than in  $\text{Al}_2\text{O}_3$ . As described in the previous section, for given irradiation conditions more aluminum is produced by irradiation of  $\text{AlN}$  than by irradiation of  $\text{Al}_2\text{O}_3$ . Also the oxide layer produced in  $\text{AlN}$  during irradiation in an oxidizing atmosphere is much thinner than that produced during irradiation in an oxidizing atmosphere. The Auger results strongly suggest that substoichiometric alumina is also present when  $\text{Al}_2\text{O}_3$  is irradiated in an oxidizing atmosphere. Deposition kinetics are in

complete agreement with the premise that metallic aluminum is the main cause of the electroless deposition in AlN and Al<sub>2</sub>O<sub>3</sub>. It is very likely that also substoichiometric alumina will help to catalyze the electroless deposition.

#### ACKNOWLEDGMENTS

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